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(12) **United States Design Patent** (10) **Patent No.:** **US D797,067 S**  
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(54) **TARGET PROFILE FOR A PHYSICAL VAPOR DEPOSITION CHAMBER TARGET**  
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(73) Assignee: **APPLIED MATERIALS, INC.**, Santa Clara, CA (US)

(\*\*) Term: **14 Years**

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(51) **LOC (10) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D13/182**

(58) **Field of Classification Search**  
USPC ..... D13/182; D15/144.1, 144.2, 199  
CPC ..... H01L 21/67742; H01L 21/0226; H01L 21/02263; H01L 21/02266; H01L 21/02269; H01L 21/02271; H01L 2224/75186; H01L 2224/76185; H01L 2224/76186; H01L 2221/68363  
See application file for complete search history.

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(57) **CLAIM**

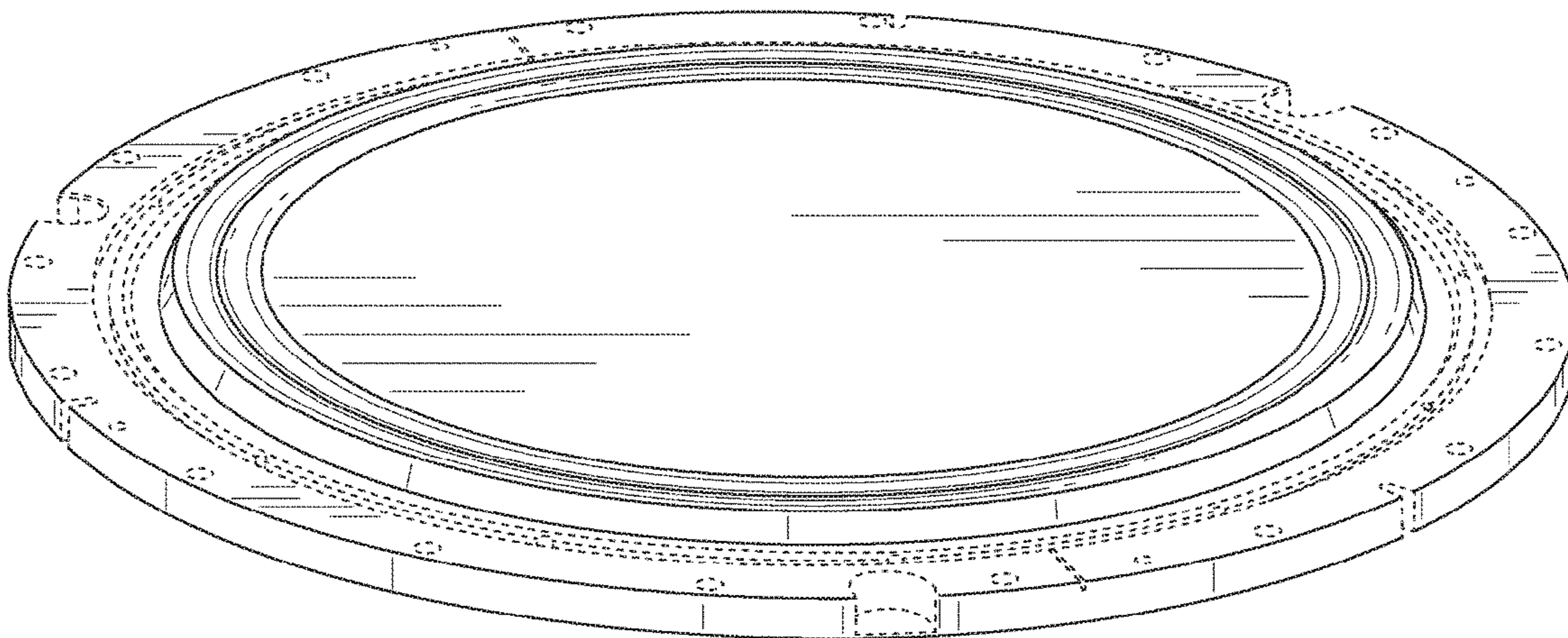
The ornamental design for a target profile for a physical vapor deposition chamber target, as shown and described.

**DESCRIPTION**

FIG. 1 is a perspective view of a target profile for a physical vapor deposition chamber target, showing our new design; FIG. 2 is a top plan view thereof; FIG. 3 is a bottom plan view thereof; FIG. 4 is a right side elevation view thereof; FIG. 5 is a left side elevation view thereof; FIG. 6 is a back elevation view thereof; FIG. 7 is a front elevation view thereof; and, FIG. 8 is a cross sectional view taken along line 8-8 in FIG. 2.

The broken lines in FIGS. 1-8 represent unclaimed environment and form no part of the claimed design.

**1 Claim, 6 Drawing Sheets**



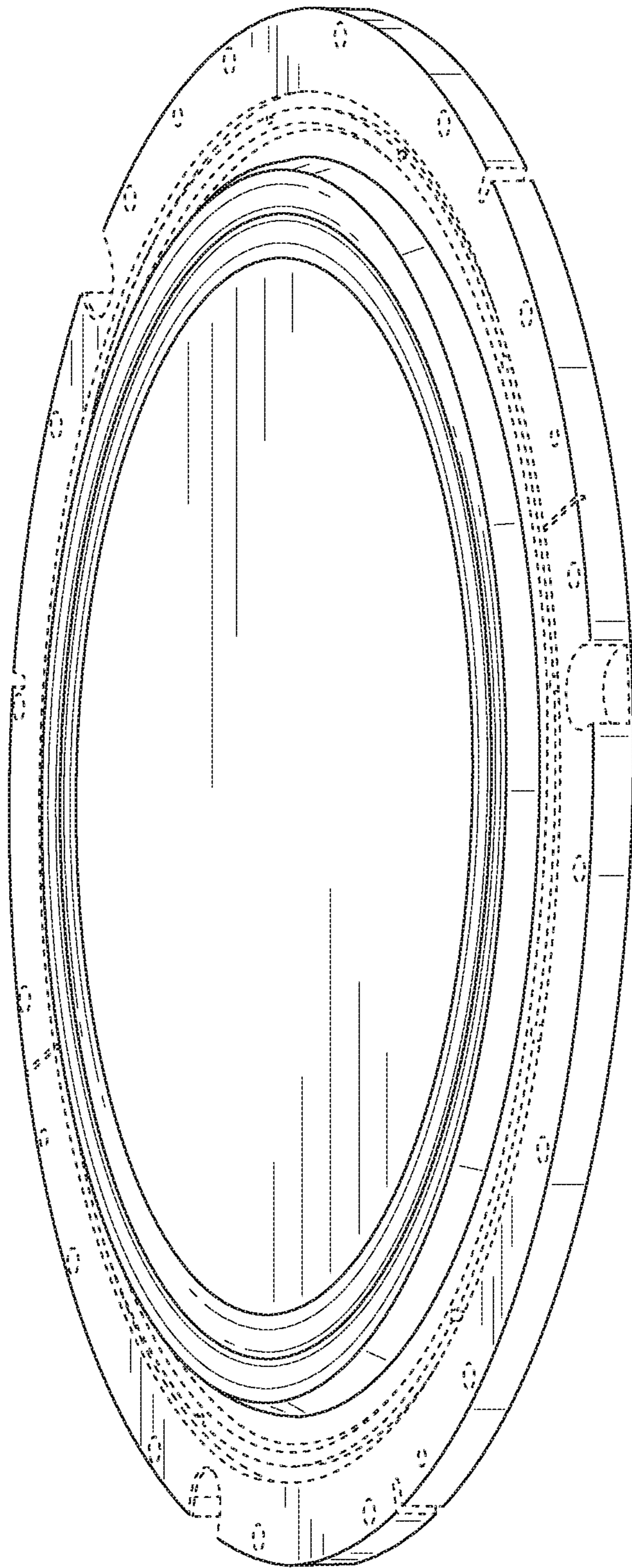


FIG. 1

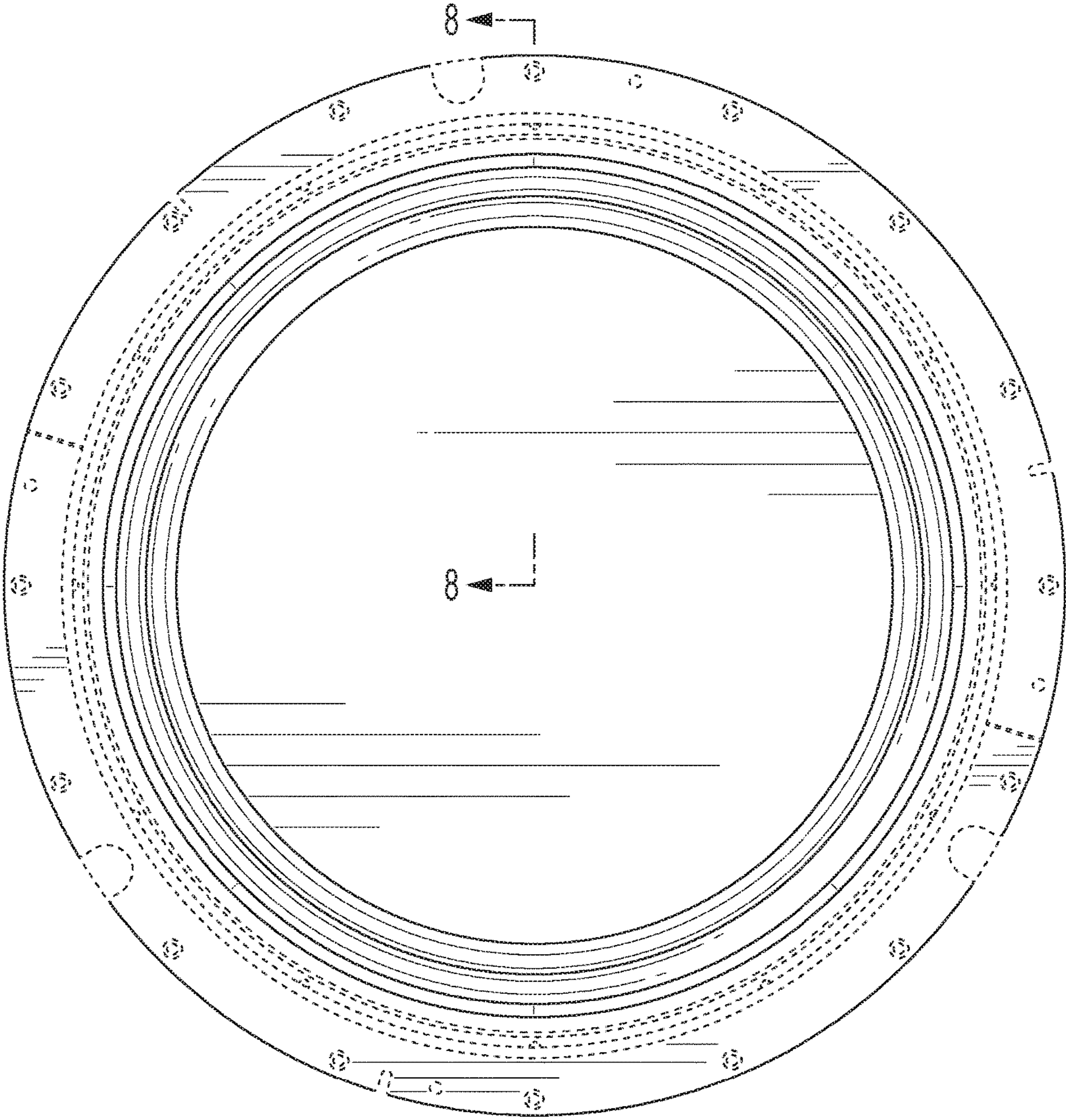


FIG. 2

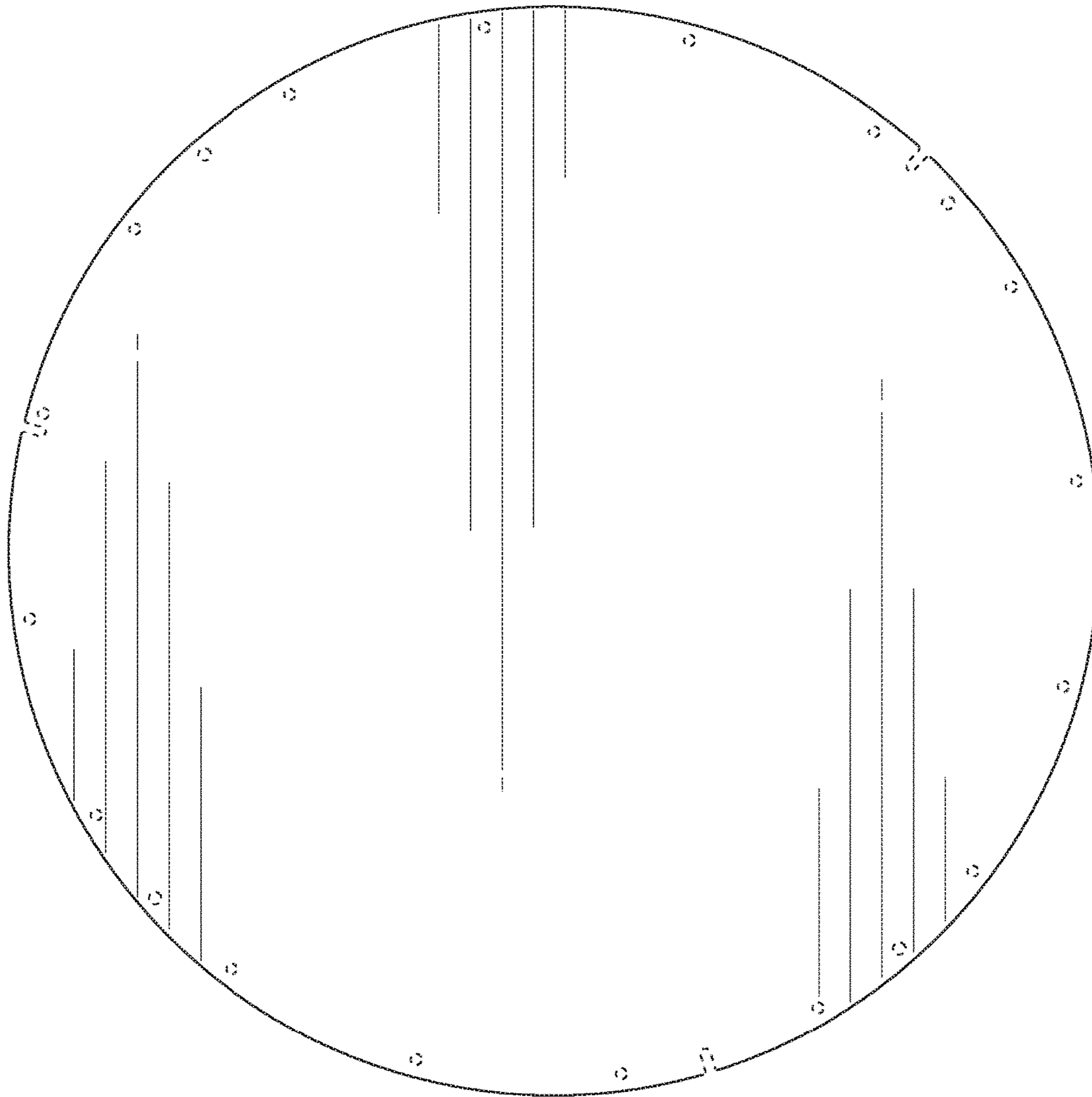


FIG. 3

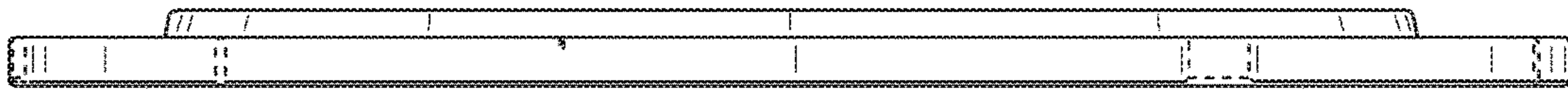


FIG. 4

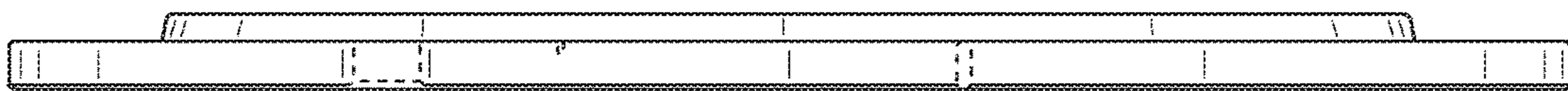


FIG. 5

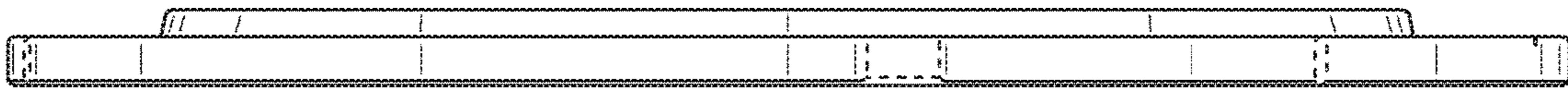


FIG. 6

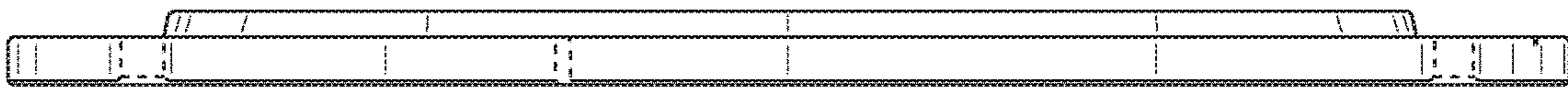


FIG. 7

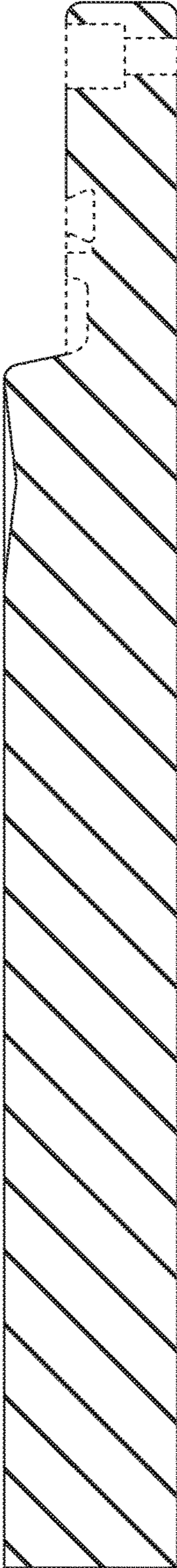


FIG. 8